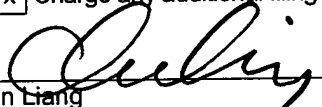


AMENDMENT TRANSMITTAL LETTER			Docket No. 108298727US	
Application No. 10/636,021-Conf. #1017	Filing Date August 6, 2003	Examiner E. B. Chen	Art Unit 1765	
Applicant(s): Palsulich et al.				
Invention: MICROFEATURE WORKPIECE PROCESSING SYSTEM FOR, e.g., SEMICONDUCTOR WAFER ANALYSIS				
TO THE COMMISSIONER FOR PATENTS				
Transmitted herewith is an amendment in the above-identified application. The fee has been calculated and is transmitted as shown below.				
CLAIMS AS AMENDED				
	Claims Remaining After Amendment	Highest Number Previously Paid	Number Extra Claims Present	Rate
Total Claims	28	- 48 =		x
Independent Claims	3	- 5 =		x
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>				
Other fee (please specify): Extension for response within first month				120.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT:				120.00
<input checked="" type="checkbox"/> Large Entity <input type="checkbox"/> Small Entity <input type="checkbox"/> No additional fee is required for this amendment. <input type="checkbox"/> Please charge Deposit Account No. <u>50-0665</u> in the amount of \$ _____. A duplicate copy of this sheet is enclosed. <input checked="" type="checkbox"/> A check in the amount of \$ <u>120.00</u> to cover the filing fee is enclosed. <input type="checkbox"/> Payment by credit card. Form PTO-2038 is attached. <input checked="" type="checkbox"/> The Director is hereby authorized to charge and credit Deposit Account No. <u>50-0665</u> as described below. <input checked="" type="checkbox"/> Credit any overpayment. <input checked="" type="checkbox"/> Charge any additional filing or application processing fees required under 37 CFR 1.16 and 1.17.				
 Chen Liang Attorney/Agent Reg. No.: 51,945 PERKINS COIE LLP P.O. Box 1247 Seattle, Washington 98111-1247 (206) 359-8000			Dated: <u>March 1, 2006</u>	



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: DAVID A. PALSULICH ET AL.

APPLICATION NO.: 10/636,021

FILED: AUGUST 6, 2003

FOR: **MICROFEATURE WORKPIECE
PROCESSING SYSTEM FOR, E.G.,
SEMICONDUCTOR WAFER ANALYSIS**

EXAMINER: ERIC B. CHEN

ART UNIT: 1765

CONF. NO: 1017

Amendment Under 37 C.F.R. § 1.114

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The present communication responds to the Office Action dated November 1, 2005 in the above-identified application, and is being filed concurrently with a Request for Continued Examination under 37 C.F.R. §1.114. Please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims beginning on page 2.